

(19) United States

(12) Patent Application Publication (10) Pub. No.: US 2005/0005705 A1

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Jan. 13, 2005 (43) Pub. Date:

(54) METHOD AND APPARATUS FOR ADJUSTABLY INDUCING BIAXIAL STRAIN

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10/837,027 (21) Appl. No.:

(22) Filed: Apr. 30, 2004

Related U.S. Application Data

(60)Provisional application No. 60/467,163, filed on Apr. 30, 2003.

Publication Classification

(57)**ABSTRACT**

An apparatus comprising a shape memory alloy is configured as a ring shaped sample holder for a transmission electron microscope and imparts uniform biaxial strain on a thin film mounted within. The sample holder responds to a change in temperature by changing the inner diameter, which imparts biaxial strain. In other embodiments, the sample holder is configured to change the inner diameter and change the strain on a thin film reversibly and repeatedly. In further embodiments, the sample holder is non circular. In still further embodiments, the apparatus is configured as a prime mover of a reversible radial actuator. Methods for making and using the apparatus are included in other embodiments.

